

Reliable Anisotropic Conductive Adhesives(ACAs) Flip Chip Technology

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COEx Conference Center (3F)

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Outline

Reliability – Thermal Cycle

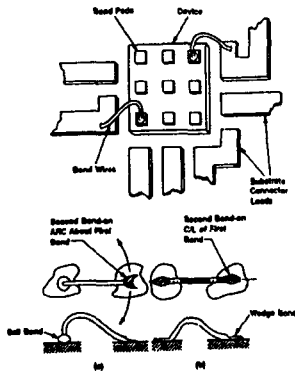
High Frequency Characteristics

Current Handling Capability

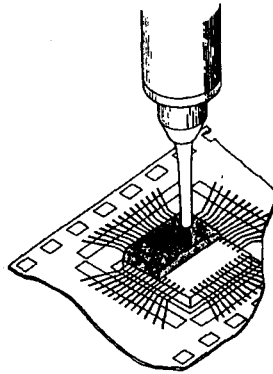
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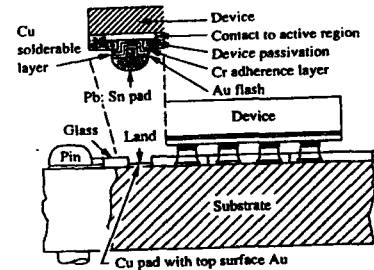
Chip Interconnection Technologies



Wire Bonding



Tape Automated Bonding (TAB)



Flip Chip

1. **Low Inductance, Capacitance**
2. **High I/O Density**
3. **Small Package Size**
4. **Self Alignment**

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Flip Chip Interconnection Methods

1. Solder Bumps – Solder Reflowing

- Evaporated solder bumps
- Electroplated solder bumps
- Screen printed solder bumps
- All joints made simultaneously by reflowing the solder

2. Non-Solder Bumps – ICAs or ACAs

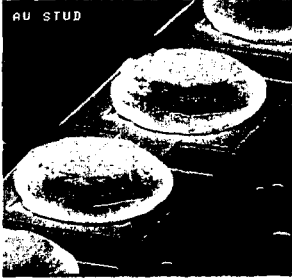
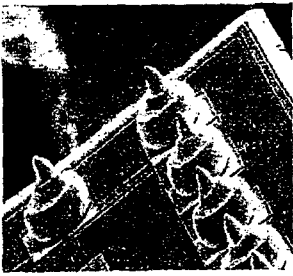
- Gold bumps
- Au stud bumps
- Electroless Ni/Au plated bumps
- Electrical interconnection medium such as ICAs and ACAs needed.

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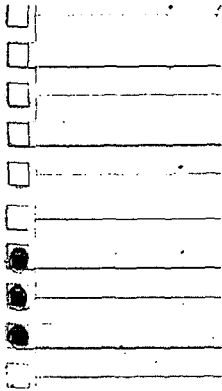
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Gold and Copper Stud Bumps

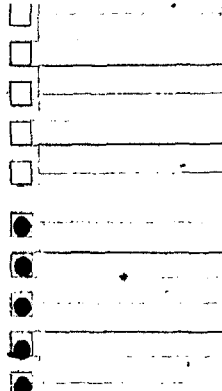
PHOTO 1 SINGLE BUMPS



Au-stud bumped testchip



Cu-stud bumped testchip



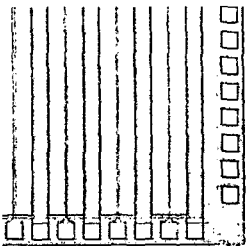
Bare Al

Stud bumping

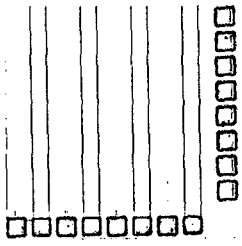
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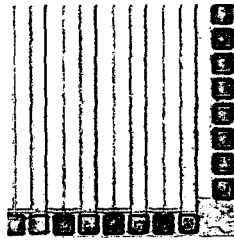
Electroless-Deposited Ni Bumps



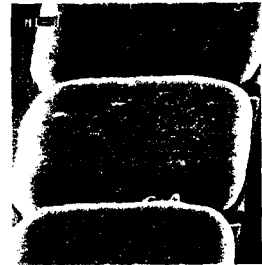
Al Pads



Ni coated bumps



Au coated Ni bumps



Electroless Ni Bumps



3-D shape of a bump

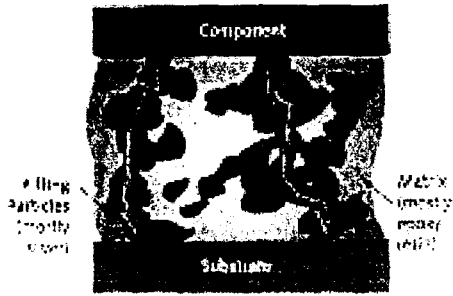
Electroless Ni Bumps Characteristics

Characteristic	Measurement	Characteristic	Measurement
Resistivity	70 $\mu\Omega$ -cm	Material analysis	P wt10%
Thickness	20 μ m	Hardness	500 \pm 50 HV
Pad size	100 \times 100 μ m ²	Pitch	150 μ m

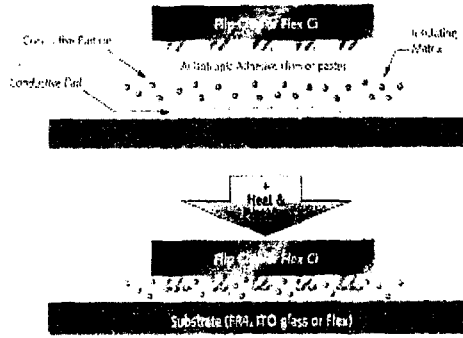
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Non-Solder Bumps need interconnection materials



Isotropic Conductive Adhesive (ICA)

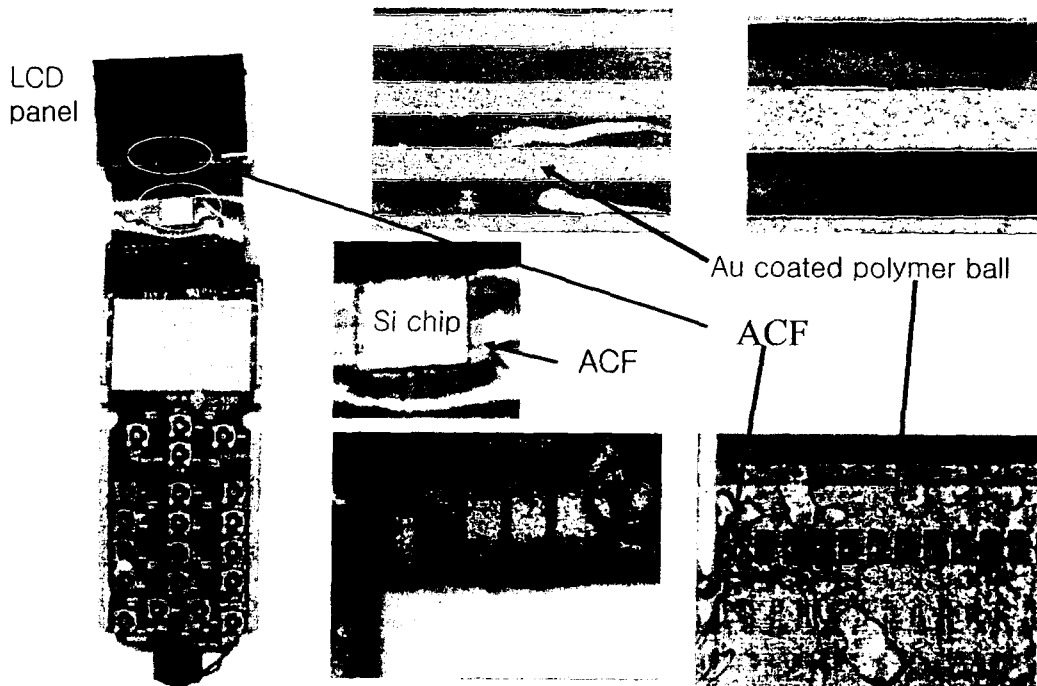


Anisotropic Conductive Adhesive(ACA)

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ACFs for LCD Applications



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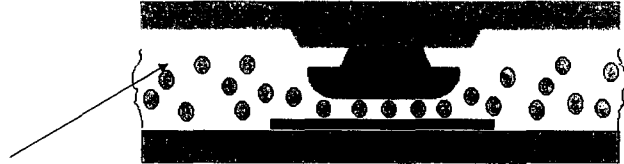
ACAs Interconnection Materials

1. Conductive Fillers

- Filler Types : metal particles (Ni, Ni/Au, solder) or
– metal coated polymer particles
- Number, Diameter, Hardness, Conductivity
- ACFs/ACAs Design Parameters optimization

2. Polymer Resin

- Polymer types:
thermosetting(epoxy) & thermoplastics
- Curing kinetics of epoxy resin



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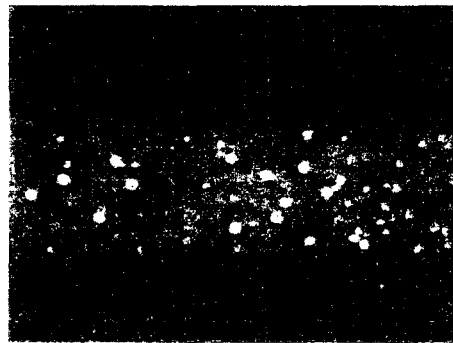
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Photo of ACFs for FCP

Plain view ×500



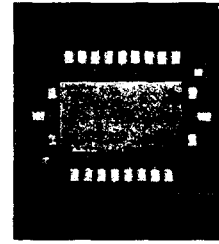
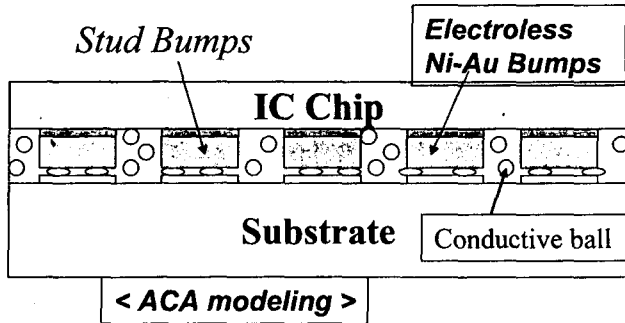
Cross-section view ×500



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ACA Flip Chip Interconnect of Electroless Ni or Au stud Bumps



Electroless Ni flip chip on a PCB using ACA

- Fine pitch interconnection capability (40 μm)
- Cost-effective packaging method
(No UBMs, easy & reduced no. of processing)
- Low Temperature process (<180 C)
- Good Mechanical and Electrical properties
- Green Processes (No flux, No solvents, No Pb)

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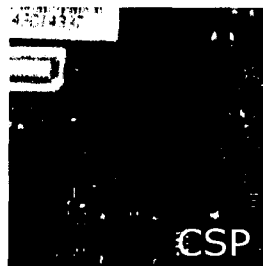
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ACF for FCP Applications

- CSP (Chip Size/Scale Package)
Bare Chip bonding on ceramic, BT-resin, FR-4, FPC, etc
- MCM (Multi-Chip Module)
Bare chip mounting as well as other electronic components.
- COF (Chip on Flex/Film)
Bare chip bonding on TAB, FPC, Smart card, RF Tag, Rigid/Flex hybrids and other flexible substrates.



MCM



CSP

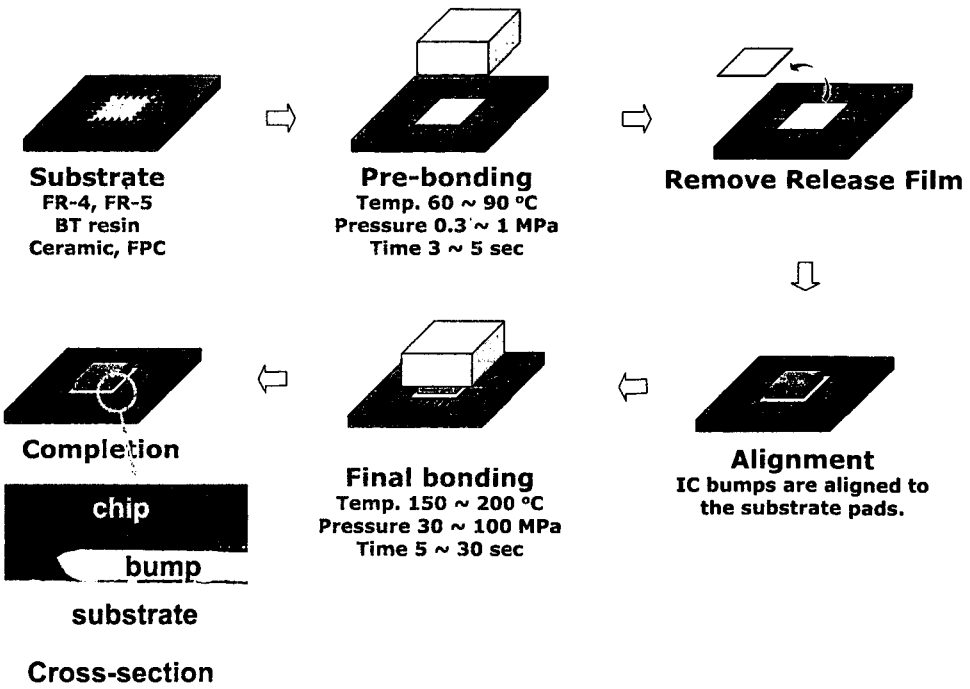


COF

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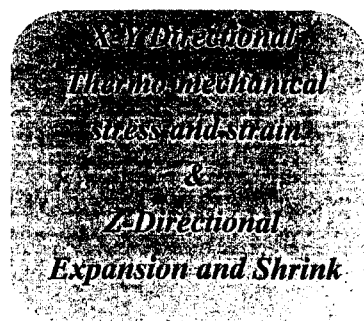
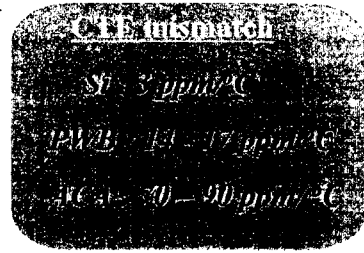
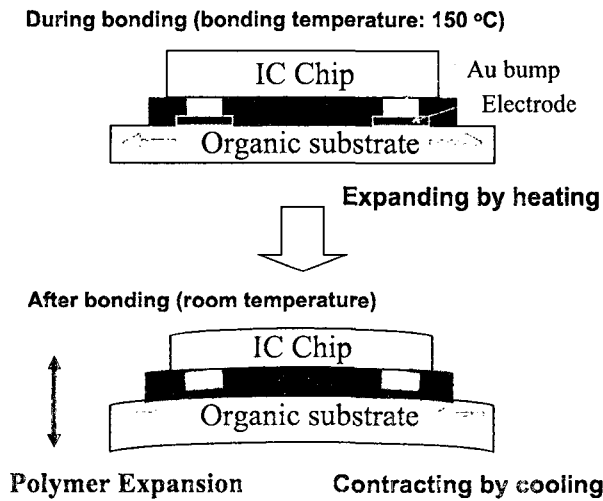
Flip chip Assembly using ACFs



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ACA Flip Chip on Organic Substrates Problem

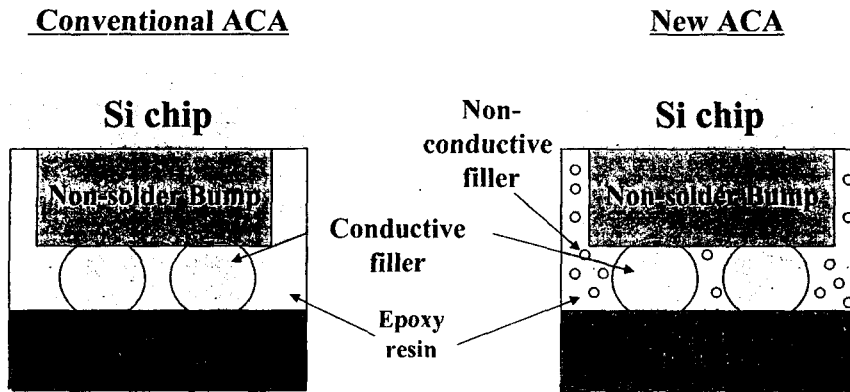


Low CTE adhesives with underfill functions

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Newly Modified ACAs



- Modification of adhesive resin, mixed concept of ACA and underfill : CTE, modulus and dielectric constant

U.S. patent 6,238,597 issued, Japan and Korea patent pending : 03/99

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Understanding of the effect of non-conductive fillers on the ACA formulation

- The thermo-mechanical properties of cured ACA materials
 —————→ Reliability enhancement of ACA flip chip assembly on organic substrates
- The dielectric properties of cured ACA materials
 —————→ High frequency electrical properties enhancement of ACA materials for High Frequency Applications
- Current Handling Capability of ACA materials

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ACA Material Systems

1. Fillers

- Conductive fillers : 5 micron-sized Ni particles
 - Non-conductive fillers : 1 micron-sized SiO₂ particles
- Both type of fillers need surface modification to be uniformly dispersed in polymer matrix

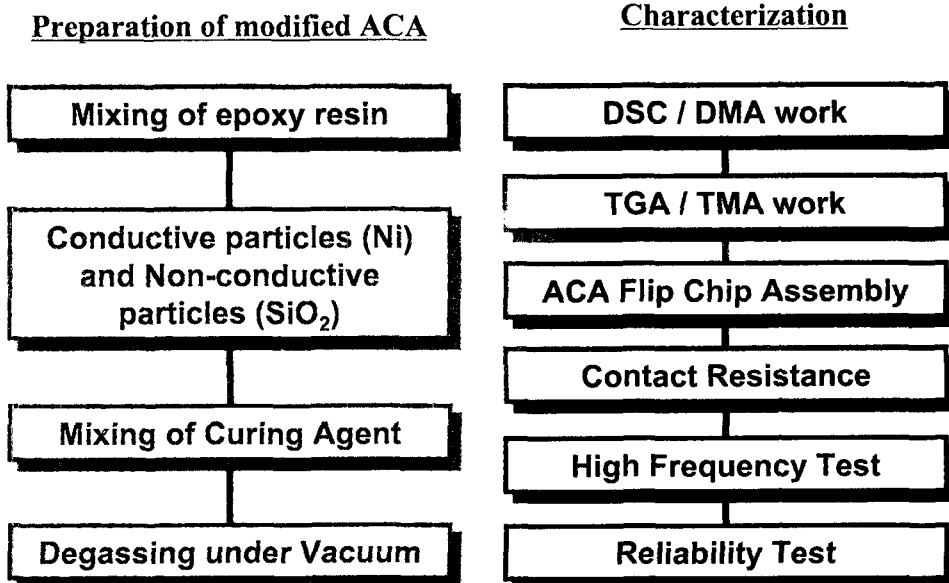
2. Polymer Matrix

- Thermoset Epoxy: Bisphenol A type liquid epoxy
- Curing agent: imidazole type curing agent

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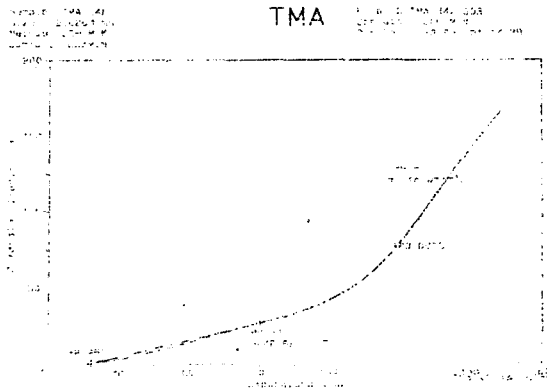
Experimental Procedures



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Material Characterization: TMA and TGA Results



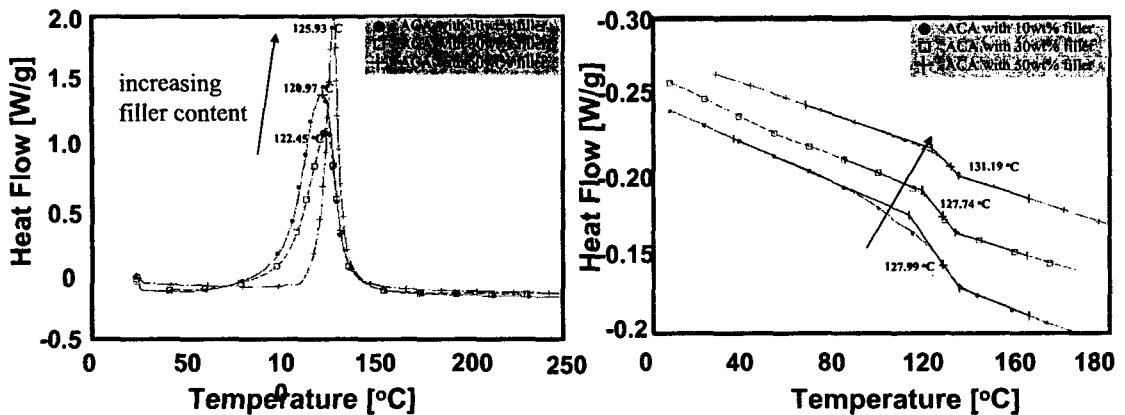
ACA composite	$\alpha 1$ (ppm/°C)	$\alpha 2$ (ppm/°C)
ACA with 0 wt% filler	58.4	3450
ACA with 10 wt% filler	51.3	1740
ACA with 30 wt% filler with A epoxy resin	43.4	445
ACA with 30 wt% filler with B epoxy resin	42.8	245

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Material Characterization : DSC Results

Differential Scanning Calorimeter



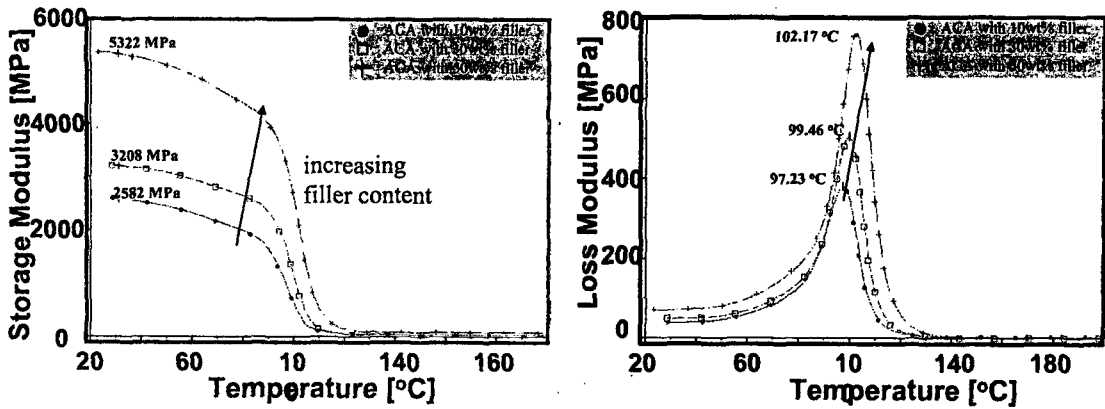
As Filler content ↑, T_g ↑ ($\Delta 4^\circ\text{C}$)

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Material Characterization : DMA Results

Dynamic Mechanical Analysis



As Filler content ↑, Storage modulus and Tg ↑

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Summary of New ACA Material Properties

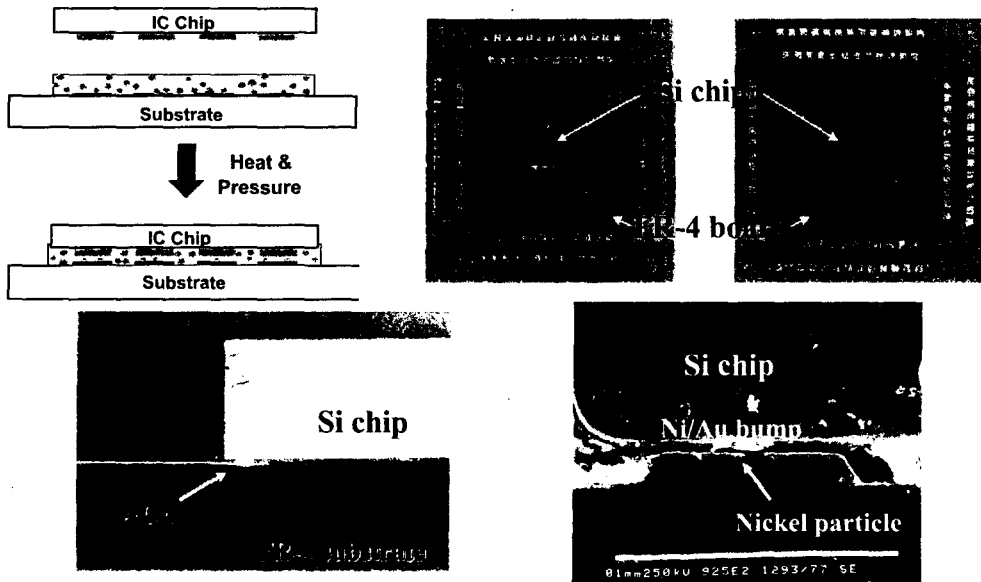
As the content of non-conductive fillers increased,

	Increase	Decrease
Storage modulus	☑	
Tg	☑	
Curing onset temperature	☑	
Curing peak temperature		
CTE below Tg		☑
Dielectric constant		☑

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Flip-chip Processes Using ACAs

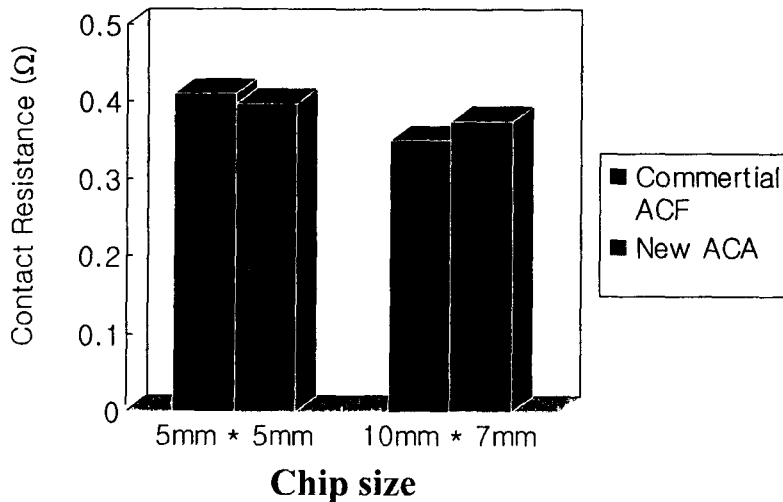


Cross-section image of ACA Flip-chip joint

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Contact Resistances of New ACA Interconnections

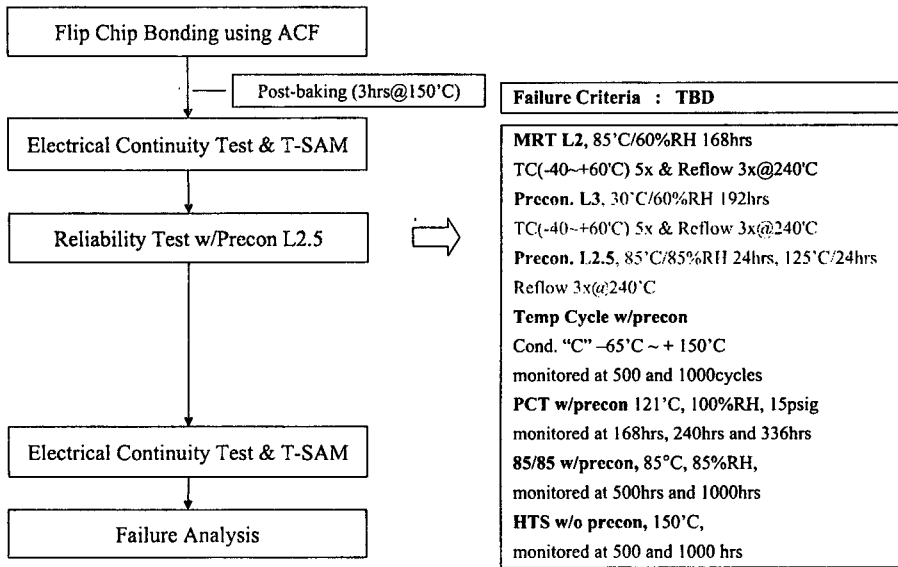


Electrical Conductivity of New ACA and Commercial ACF

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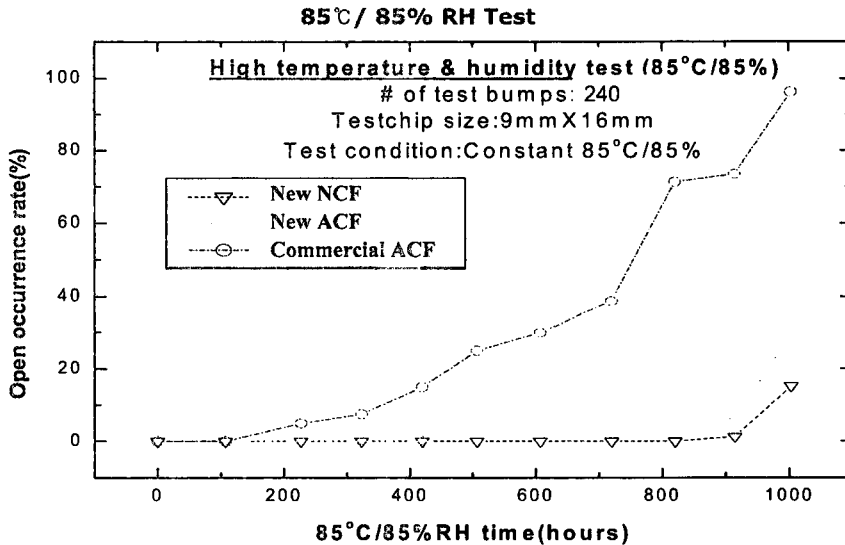
Reliability Test of ACF for FCP



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Reliability of New ACF/NCF



Bonding Condition : 180 °C, 30 sec, 40 MPa, substrate heating, hot bar 125°C

Open occurrence rate : # of failed interconnects / total # of bumps tested

Definition of failed bump : 100 % increase of initial contact resistance

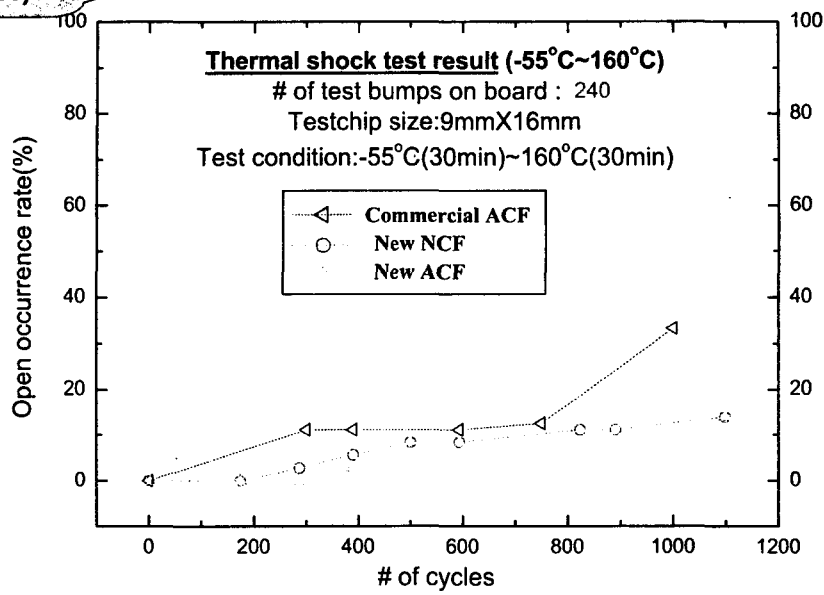
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Reliability of New ACF/NCF

After IR Reflow
(2 Times)

Thermal Shock Test (-65 ~150°C)

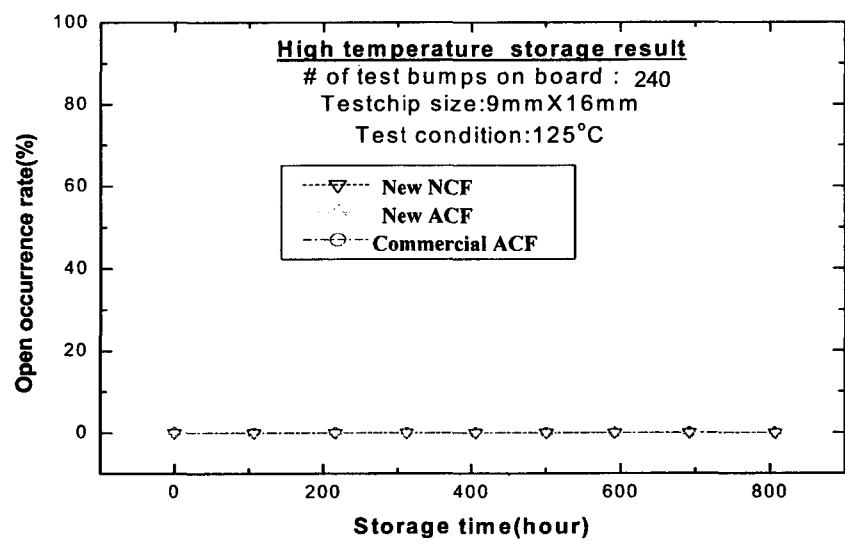


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Reliability of New ACF/NCF

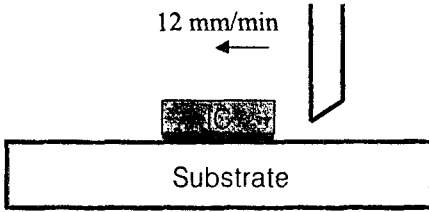
High Temp. Storage Test (125°C)



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Adhesive Strength Test Method



ACF width : 4 mm

Bonding Condition : 180°C, 40MPa, 20s

Substrate : FR-4 (40 mm * 40 mm)

Test chip : 3 mm^φ, 0.4 mm^t, bumpless

Pattern : Cu ½ ounce Ni, Au plating

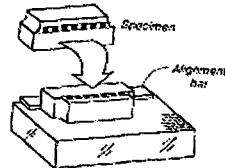
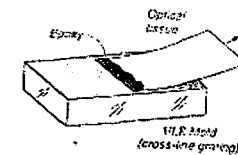
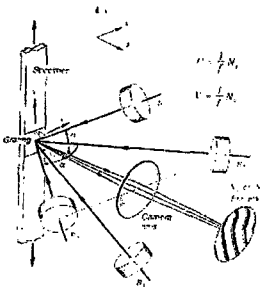
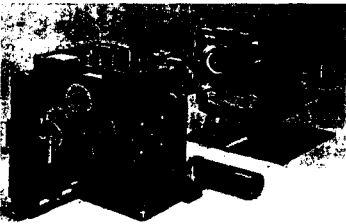
Sample	Initial	After 85°C/85%RH/500hrs
New ACF-1	IC fracture	IC fracture
New ACF-2	IC fracture	IC fracture

- Strong adhesion of New ACFs on organic substrate

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Micro-Moire Fringe Analysis



Oven

Relationship between fringe order and displacement

$$U_{(x,y)} = N_{x(x,y)} / f$$

$$V_{(x,y)} = N_{y(x,y)} / f$$

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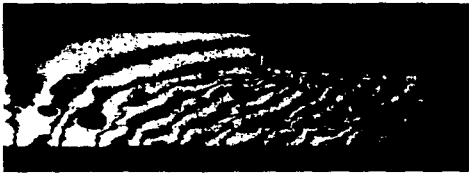
U Field (x-direction) Deformation



10 wt% SiO₂

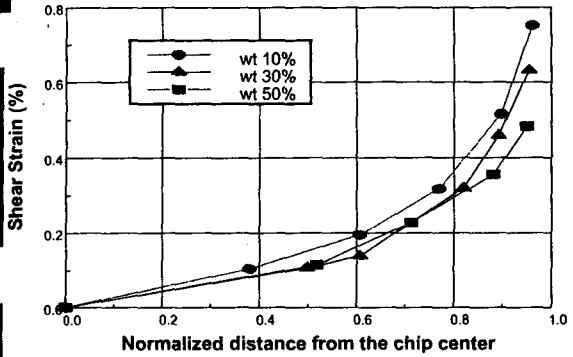


30 wt% SiO₂



50 wt% SiO₂

$\Delta T = 80\text{ }^{\circ}\text{C}$

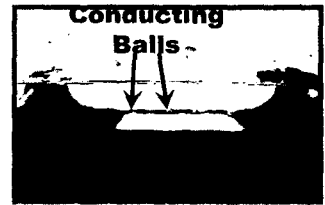
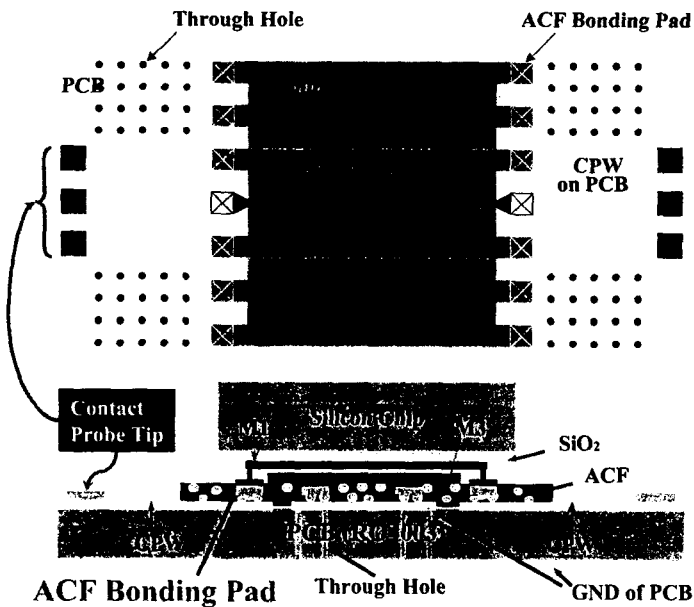


Reduced Shear Strain

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Test Chip and PCB for High Frequency Measurement



CPW on PCB

Microstrip on Silicon

Minimize the Parasitic and Silicon Effect

Multi-through Hole

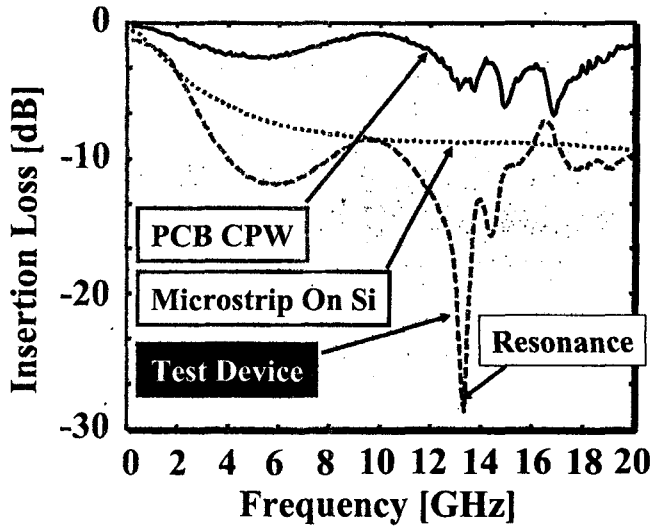
Multi-via Hole for Low

Impedance Ground

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Measured Insertion Loss of Conventional ACFs



Measured Insertion Loss Using a Network Analyzer from 200 MHz to 20 GHz

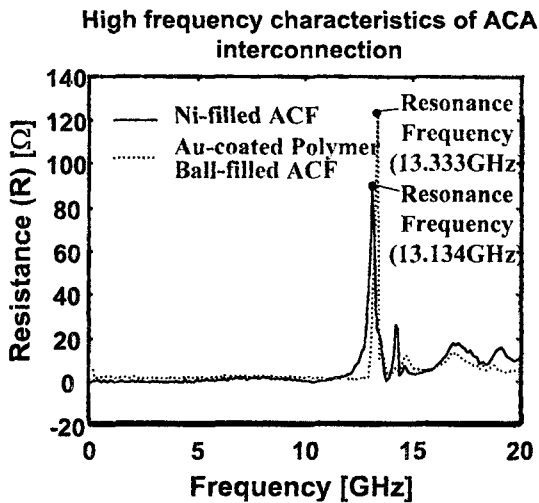
Resonance Frequencies around 13 GHz.

Parallel LC Resonance

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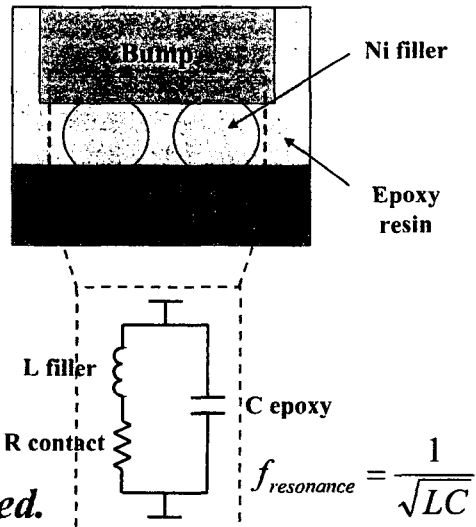
High Frequency Properties of Flip Chip ACAs



• *Low dielectric adhesive is needed.*

Ref. IEEE Trans. On CPT Vol. 22, No.4, pp.575-581

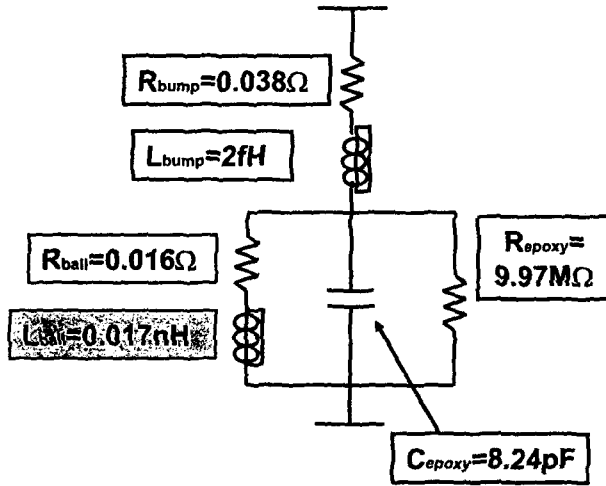
Equivalent circuit and resonance frequency



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Final Equivalent Circuit of Conventional ACF Interconnect



Extracted Equivalent Circuit Model of the $100\mu\text{m} \times 100\mu\text{m}$ Flip-chip Interconnection using Au-coated polymer ball-filled ACF

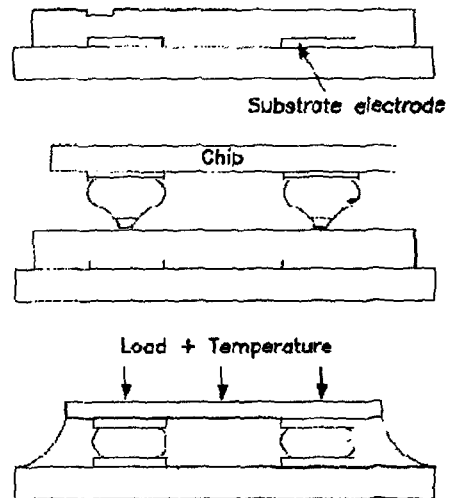
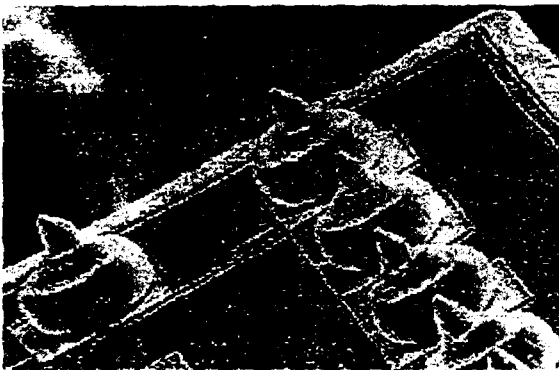
Useful up to 15GHz

Low Loss and Dielectric Constant of the Epoxy Resin

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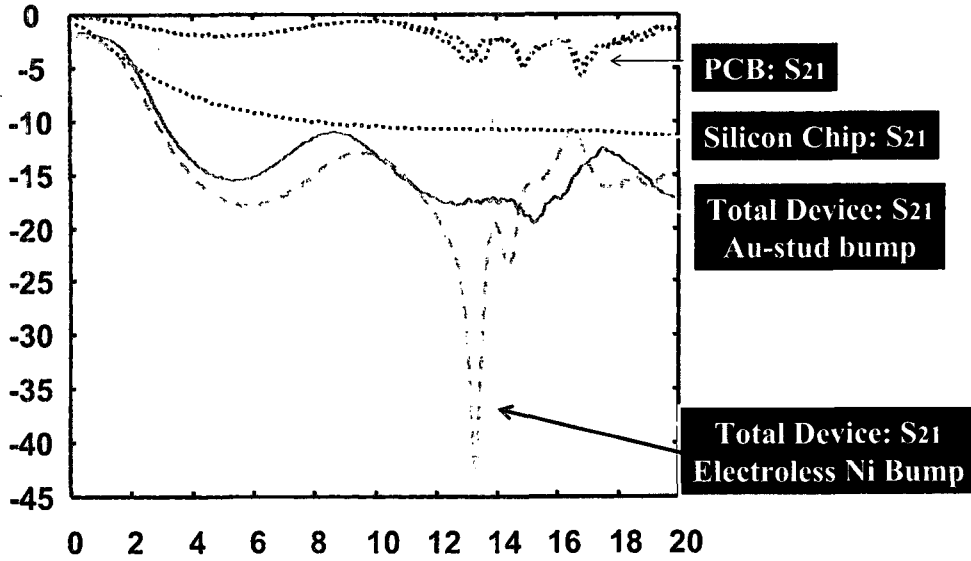
High frequency behavior of gold stud bump ACF flip chip



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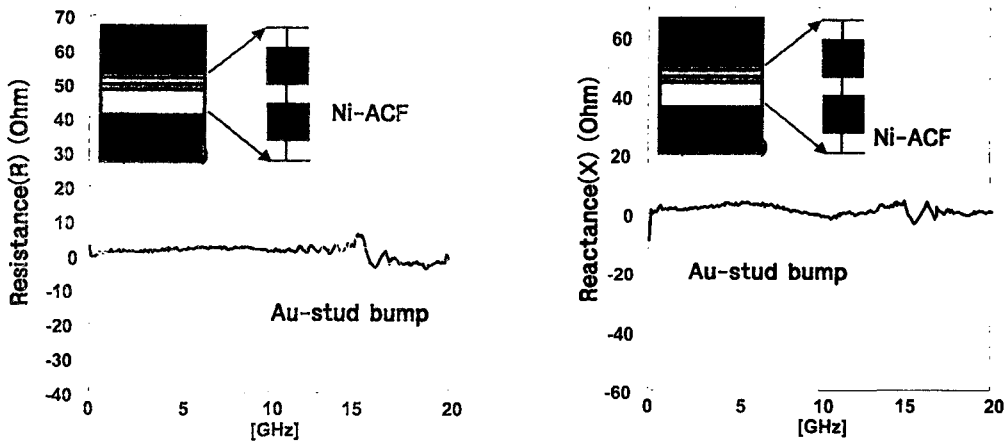
High frequency behavior of Au stud bump with Conventional ACFs



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Impedance parameter extraction : Au-stud bump

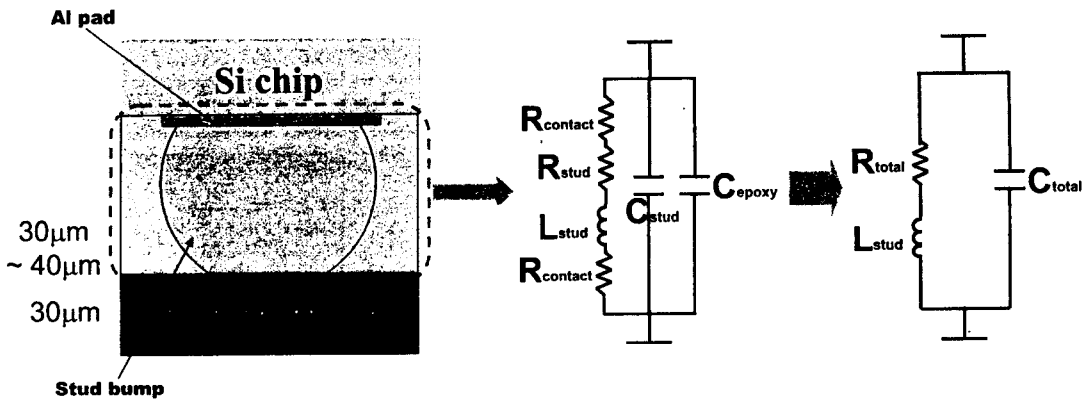


- ✓ Resonance phenomena was not occurred
- ✓ At microwave frequency, impedance is constantly maintained (Good high frequency characteristics)
- ✓ Packaging of microwave device within 20GHz operation freq.

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Stud bumps model

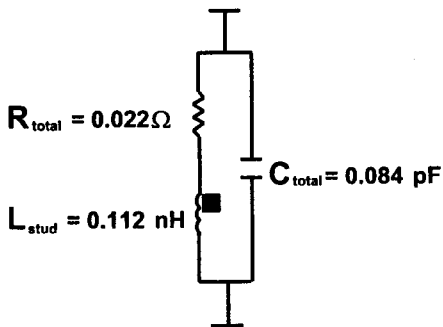


- ✓ Modeling for equivalent circuit extraction
- ✓ Modeling system
= stud bump system + insulating epoxy system

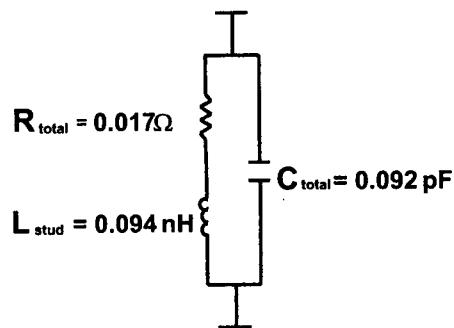
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Equivalent CKT modeling of stud bumps



Au-stud bump



Cu-stud bump

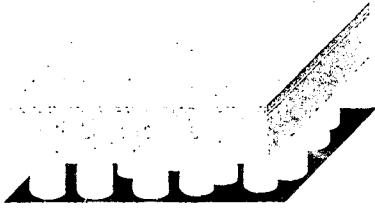
- ✓ C_{total} was greatly reduced when compared with ACF (2 order smaller)
- ✓ This reduction is originated from the structural difference of interconnection
- ✓ Availability of this equivalent circuit was verified

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Origin of reduced capacitive coupling

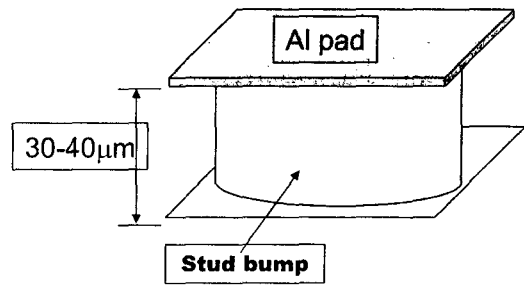
Electroless Ni Bump



Conducting ball(Ni)

ACF interconnect structure

Stud Bump



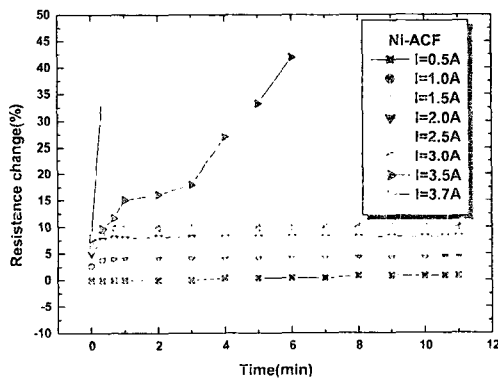
Stud bumps interconnect structure

- ✓ Capacitive coupling is originated from E-field interaction
- ✓ Capacitive coupling ($\sim 1/L^2$)
 - = (1)chip-substrate proximity effect + (2)inter-conducting system effect
- ✓ Therefore, capacitive coupling of ACF is larger than that of stud bumps

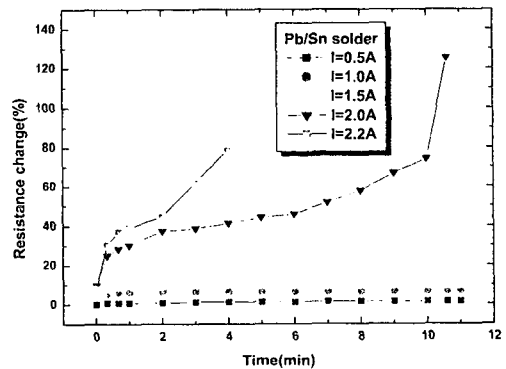
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ACF Current Handling Capability: Resistance Changes vs. Current and Times



Ni ACF(pad 500 μm)

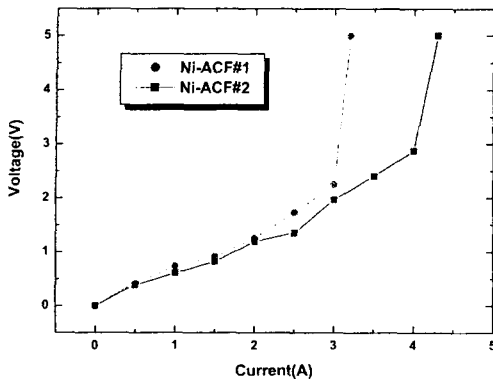


Solder (bump 750 μm dia.)

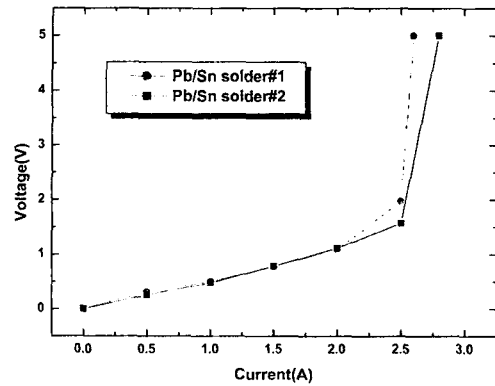
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Current Handling Capability of ACF and Solder Flip Chip



Ni ACF(pad 500 μm)



Solder (bump 750 μm dia.)

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ACF Technology Conclusions

- ACF Technology – Mature Technology
 - Display packaging technology materials
 - Mechanism, formulation, manufacturing well understood
- ACF Materials innovation under progress
 - Low temperature, fast curing ACF
 - Fine pitch ACFs
 - Flip chip ACFs for organic boards
- ACF flip chip
 - Proven at high frequency applications
 - Cost competitive
 - Materials, equipment, bumping – infrastructure built
- The newly modified flip chip ACFs – reliability proven technology
- Applications – memory, telecommunication, appliances, etc.

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